有四块硅样品,其掺杂情况分别是:

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乙. 含硼和磷各1×10¹⁷ cm⁻³

室温下,这些样品的电子迁移率由高到低是(),电导率由高到低是()。

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To calculate the drift current density for a given electric field strength in a semiconductor device. Consider a GaAs sample at T=300 K with doping concentrations of $N_{\rm A}=0$ and $N_{\rm D}=10^{16}\,{\rm cm}^{-3}$. Assume complete ionization and assume electron and hole mobility are 8500 and 400 cm²/V·s, respectively. Calculate the drift current density if the applied electric field strength is E=10 V/cm.

计算已知电场强度下的漂移电流密度。 $T=300~{\rm KH}$,GaAs的掺杂浓度分别为 $N_{\rm A}=0~{\rm Al}~N_{\rm D}=10^{16}~{\rm cm}^{-3}$ 。电子和空穴的迁移率分别为8500 cm²/V·s 和 400 cm²/V·s。 若外加电场强度为 $E=10~{\rm V/cm}$,求漂移电流密度。已知 $n_i=1.8\times10^6~{\rm cm}^{-3}$ 。

Solution:

Since
$$N_D >> n_i$$
, $N_A = 0$

Then:

$$\begin{cases} n_0 \approx N_D = 10^{16} \,(\text{cm}^{-3}) \\ p_0 = \frac{n_i^2}{n_0} = \frac{(1.8 \times 10^6)^2}{10^{16}} = 3.24 \times 10^{-4} \,(\text{cm}^{-3}) \end{cases}$$

$$\therefore J_d = nq\mu_n E + pq\mu_p E
\approx nq\mu_n E
= (10^{16})(1.6 \times 10^{-19})(8500)(10)
= 136 (A/cm^2)$$

由此可知,非本征半导体中,漂移电流密度基本取决于多子,在半导体上加较小的电场就能获得很大的漂移电流密度

证明当电子浓度和空穴浓度为某定值时,材料电导率最小,并推导该最小电导率的表达式。

分别计算掺有下列杂质的Si在室温下的载流子浓度, 并查图得到迁移率,然后再计算电导率:

- (1) 2×10¹⁵ cm⁻³的B;
- (2) $2 \times 10^{15} \,\mathrm{cm}^{-3}$ 的B + $3 \times 10^{15} \,\mathrm{cm}^{-3}$ 的P。

解: (1) 在室温下
$$N_A$$
 = 2×10¹⁵ cm⁻³ > 10 n_i 杂质全电离,故 p_0 = N_A = 2×10¹⁵ cm⁻³ 所以 n_0 = n_i^2/p_0 = $(1.5 \times 10^{10})^2/2 \times 10^{15}$ = 1.125 × 10⁵ (cm⁻³)

• 查图得到
$$\mu_p = 440 \text{ cm}^2/\text{V} \cdot \text{s}$$

$$\sigma = nq\mu_n + pq\mu_p$$

$$\approx pq\mu_p$$

$$= (2 \times 10^{15} \times 10^6) \times (1.6 \times 10^{-19}) \times (440 \times 10^{-4})$$

$$= 14.08 (\Omega^{-1} \cdot m^{-1})$$

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(2) 在室温下
$$N_D^* = N_D - N_A = 1 \times 10^{15} \text{ cm}^{-3} > 10 n_i$$

故 $n_0 = N_D^* = 1 \times 10^{15} \text{ cm}^{-3}$
所以 $p_0 = n_i^2/n_0$
 $= (1.5 \times 10^{10})^2/10^{15}$
 $= 2.25 \times 10^5 \text{ (cm}^{-3})$

• 查图得到
$$\begin{cases} \mu_p \approx 420 \text{ cm}^2/\text{V} \cdot \text{s} \\ \mu_n \approx 1800 \text{ cm}^2/\text{V} \cdot \text{s} \end{cases}$$

Given 1 ohm·cm as a "typical" value of n-type silicon resistivity, and 100 A/cm² as a typical current density encountered in an operating silicon device, calculate typical values of electric field and electron drift velocity (T = 300 K). Taking $10^3 \text{ cm}^2/\text{V} \cdot \text{s}$ as the value of electron mobility.

Solution:

From ohm's law we have

$$J = \sigma E = \frac{1}{\rho}E$$

$$\Rightarrow E = \rho J = 1 \times 100 = 100 \text{ (V/cm)}$$

Taking 10^3 cm²/V·s as the value of electron mobility, then we have:

$$v_d = \mu E$$

= $(10^3 \text{ cm}^2/\text{V} \cdot \text{s})(100 \text{ V/cm})$
= 10^5 cm/s